

High Spatial Resolution MEMS Surface Pressure Sensor Array for Transonic Compressor IGV Measurement

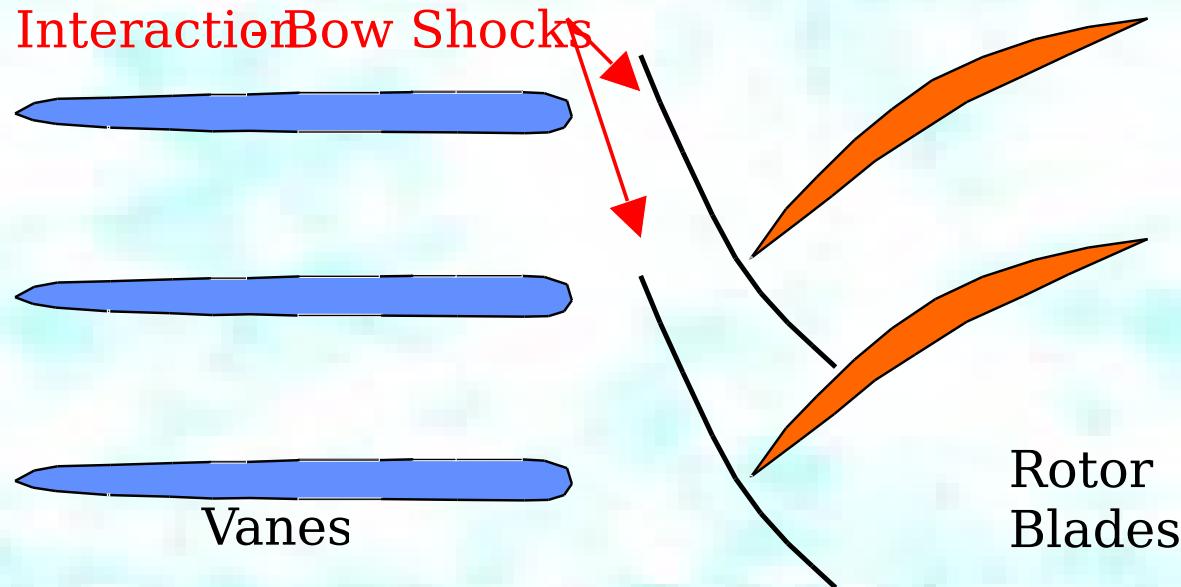
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Outline

- Introduction
- IGV Instrumentation
 - Research Facility
 - Previous Instrumentation
 - Flex Circuit Substrate
 - Pressure Transducer Dies
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- Preliminary Measurements
- Conclusions

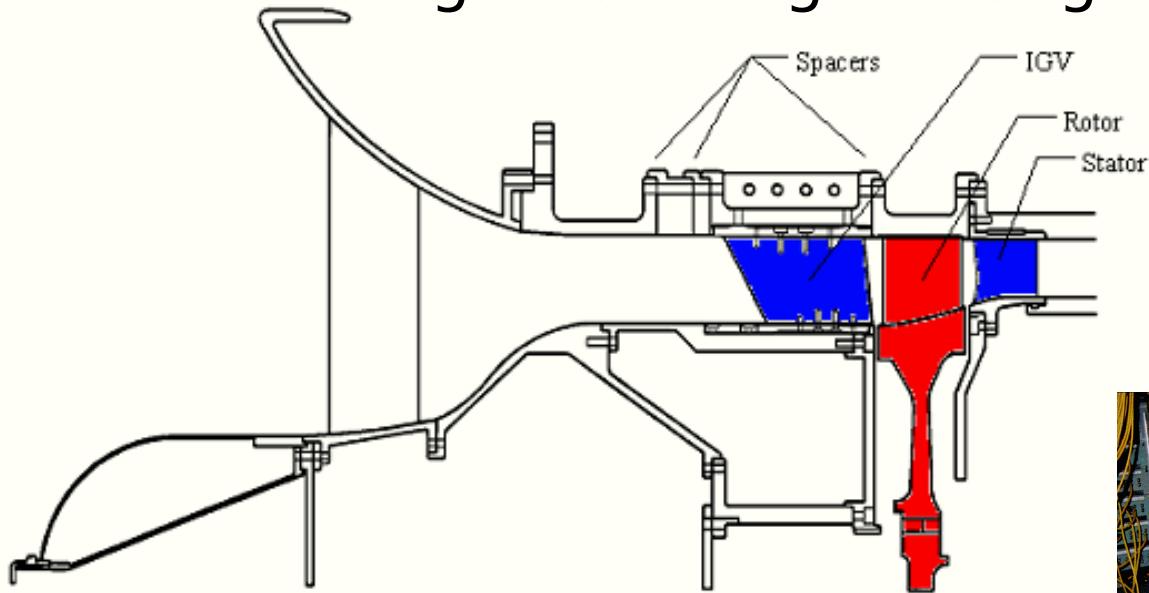
Introduction & Motivation

- Forced response is an important component of HCF analysis
 - Vane/blade interaction a principal cause of unsteady aerodynamics
 - Detailed measurements required to determine flow physics
- Shock interaction is a main driver in unsteady aerodynamics
 - Insight into bow shock flow physics is needed
 - Shock/boundary layer interaction in end-wall region is unknown
- MEMS technology is utilized to understand flow physics
 - Increased economical measurement resolution required
 - Decreased installation expense due to MEMS flex circuit technology



- Bow shocks are the primary unsteady driver
- High spatial & frequency resolution data is required to understand the complicated flow physics involved

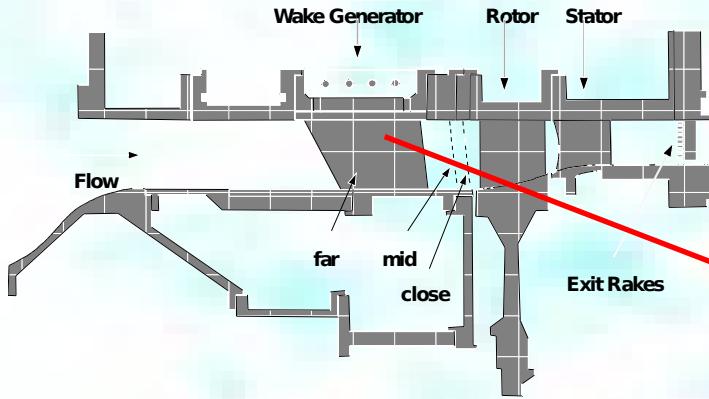
Compressor Aero Research Laboratory (CARL) Stage Matching Investigation (SMI) Rig



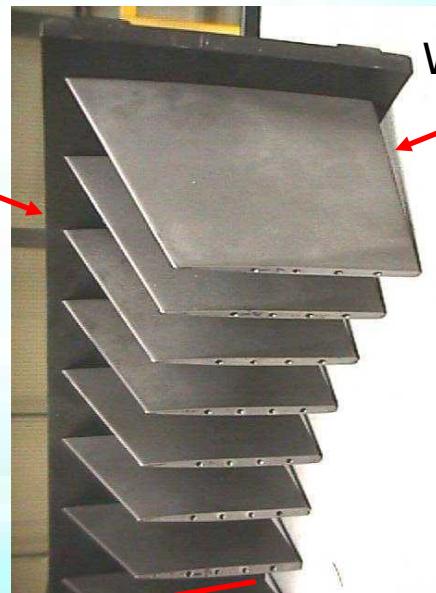
3 possible IGV/Rotor spacings:
12, 24, 40 IGV's
33 Rotor blades
49 Stator blades



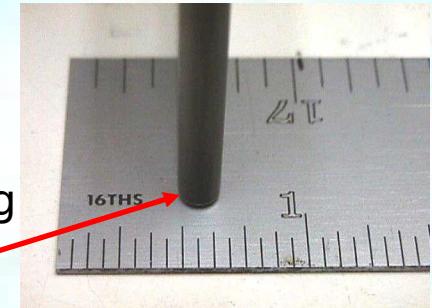
Inlet Guide Vane (IGV)



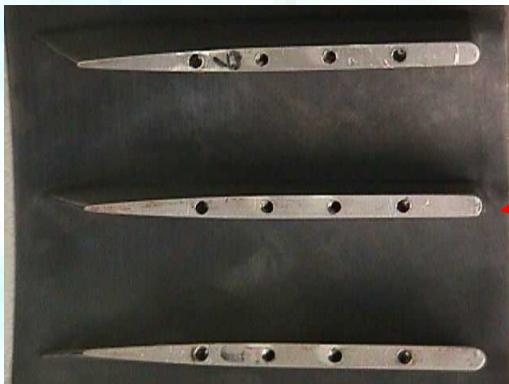
40-Strut Configuration



WG Trailing Edge



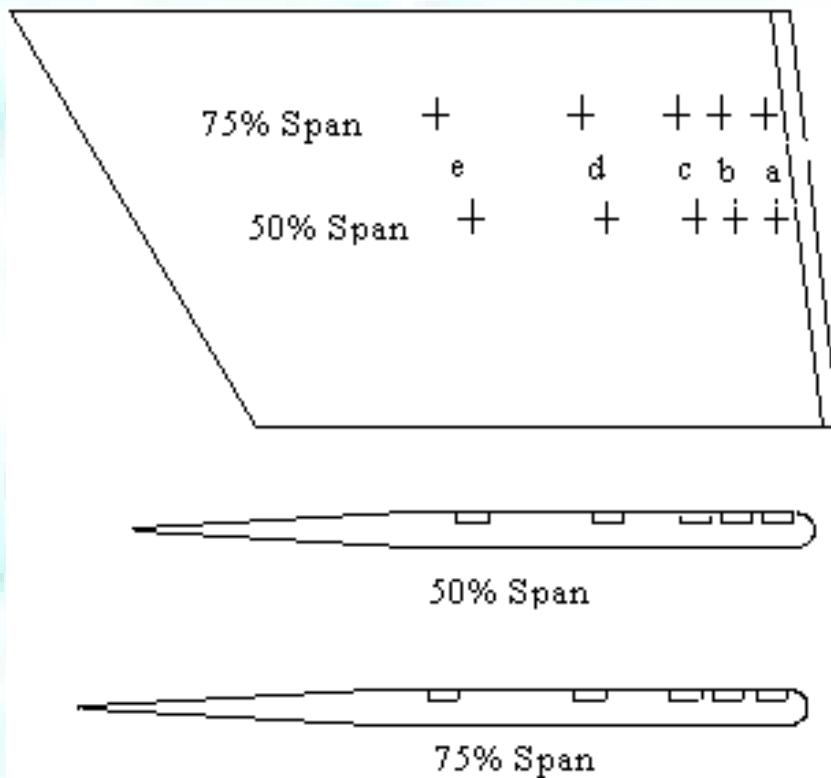
Trailing Edge Thickness
at Mid Chord
0.06



Airfoil Cross Section Hub

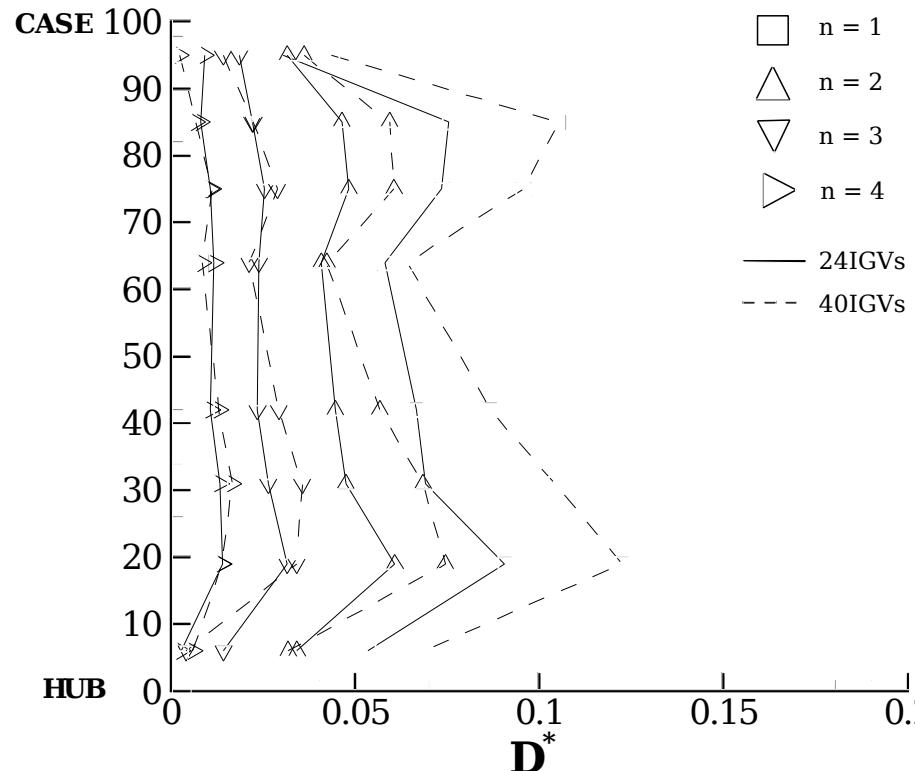


Previous Instrumentation



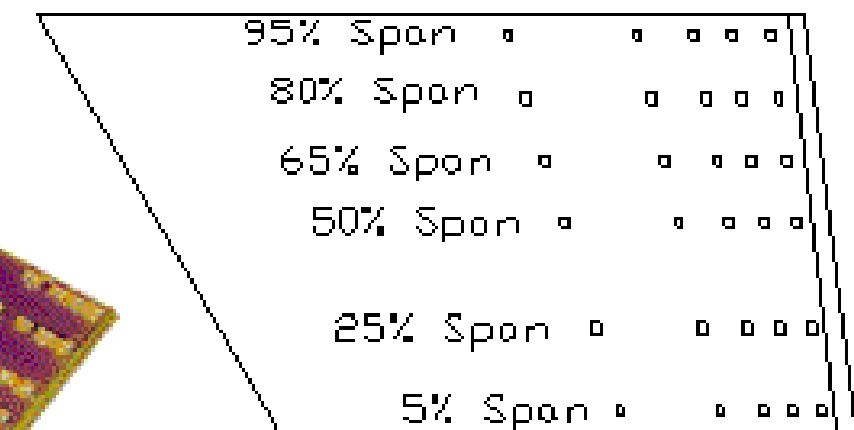
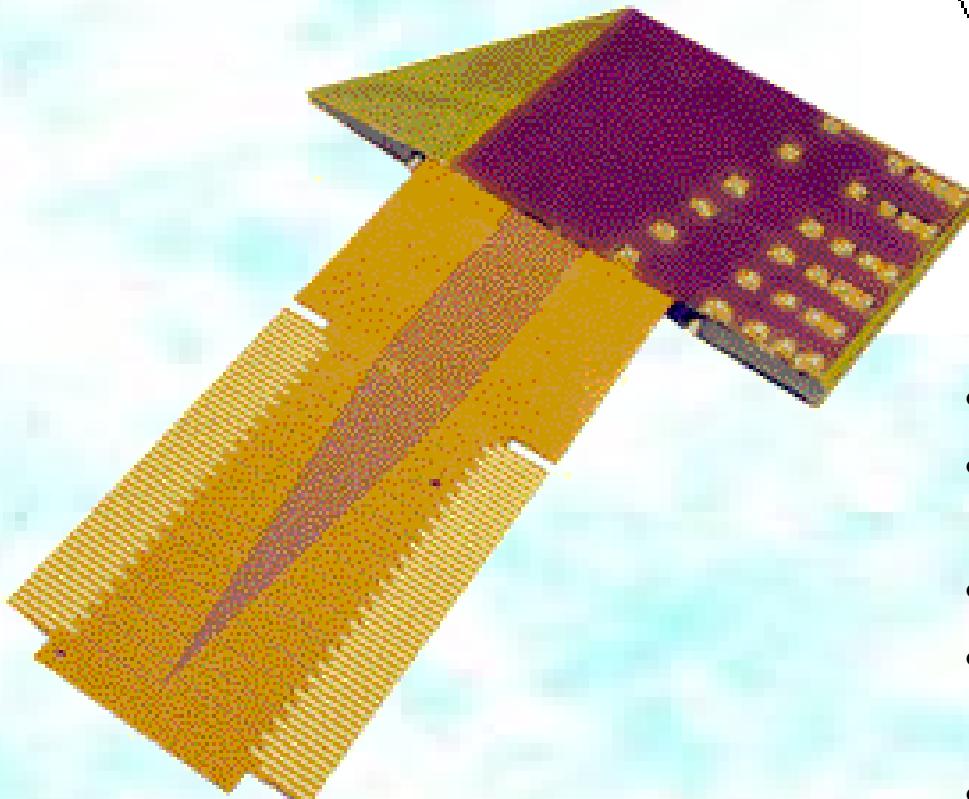
- 10 Kulite LQ-125 pressure transducers
- 25 psia
- 95%, 89%, 83%, 70%, 50% chordwise locations
- \$25,000

Probasco et al. 1997



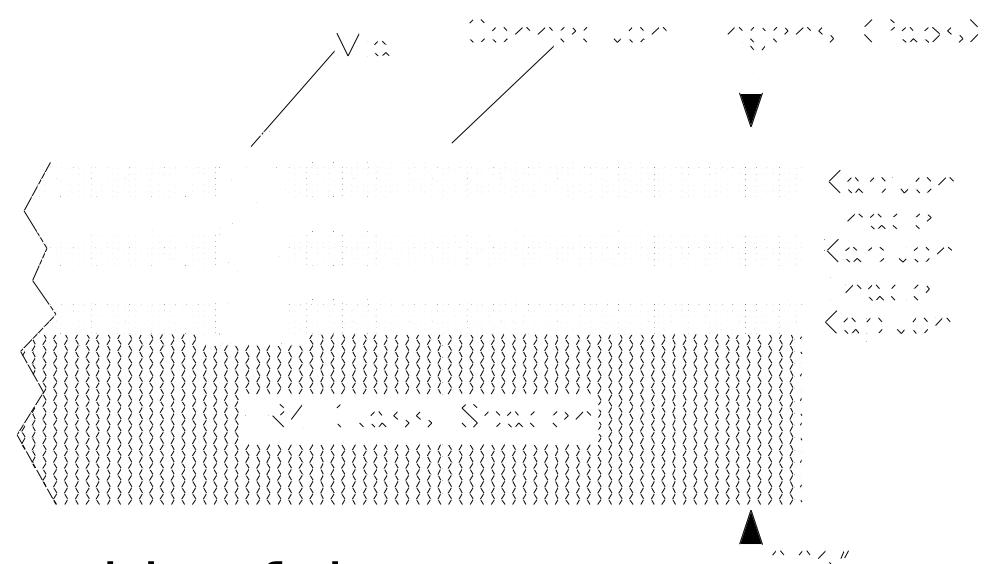
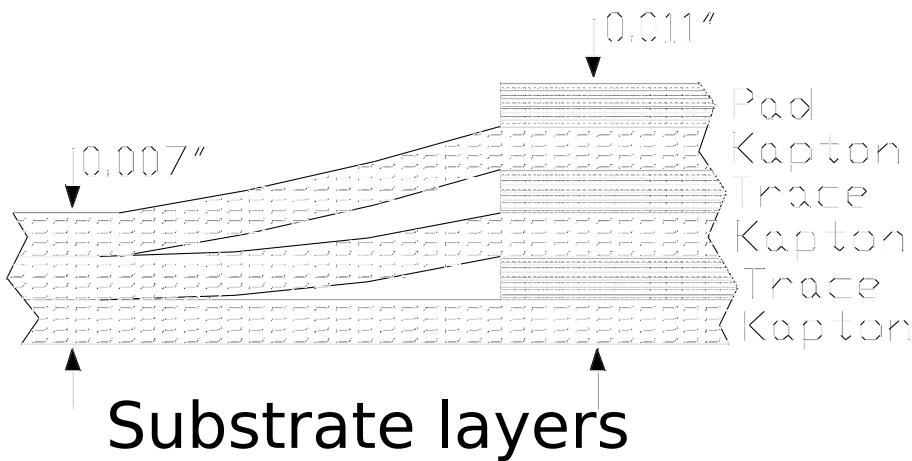
- Vortical forcing function research by Koch et al. 2000 demonstrates the 3-D nature of flow in the SMI rig

MEMS Sensor Array



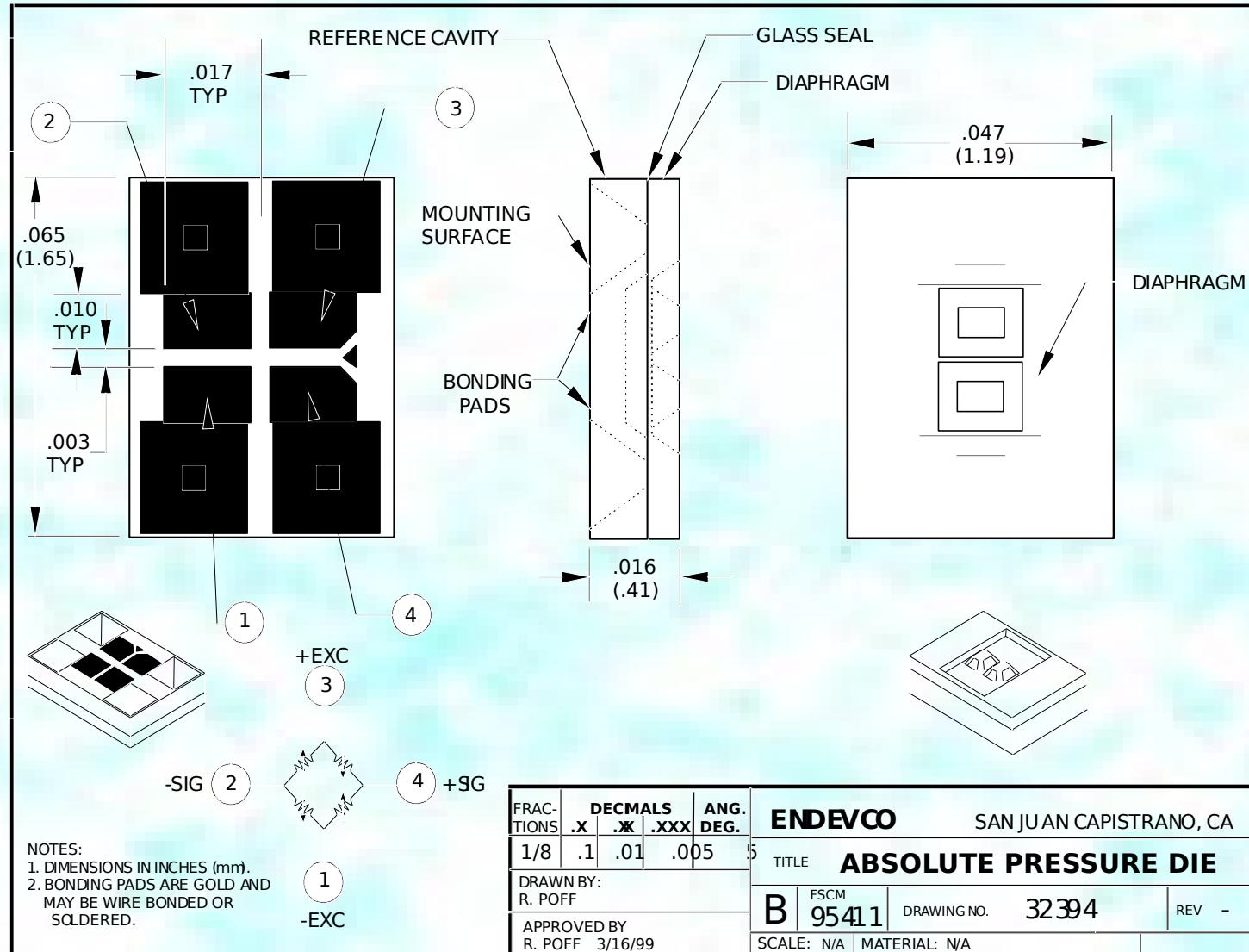
- 30 Sensors - 15 psia
- 3-layer flex circuit substrate ~ 0.01" thick
- ~ 0.03" total thickness
- 95%, 90%, 85%, 77%, 60% chordwise locations
- \$40,000

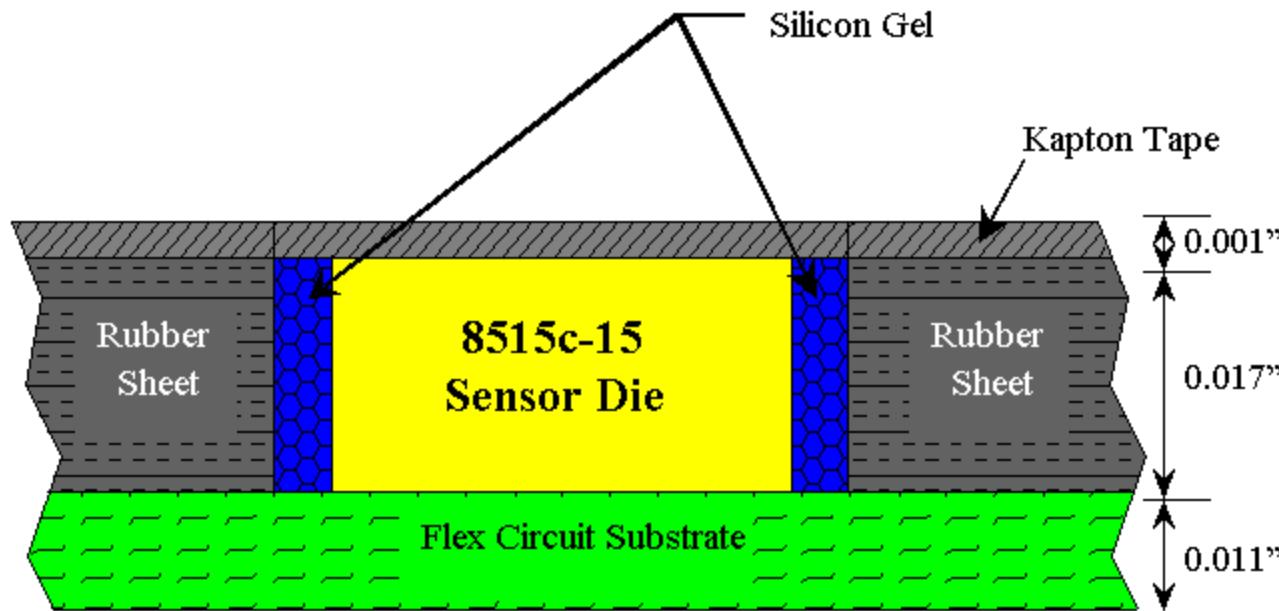
Flex Circuit Substrate



Outside of the test
section

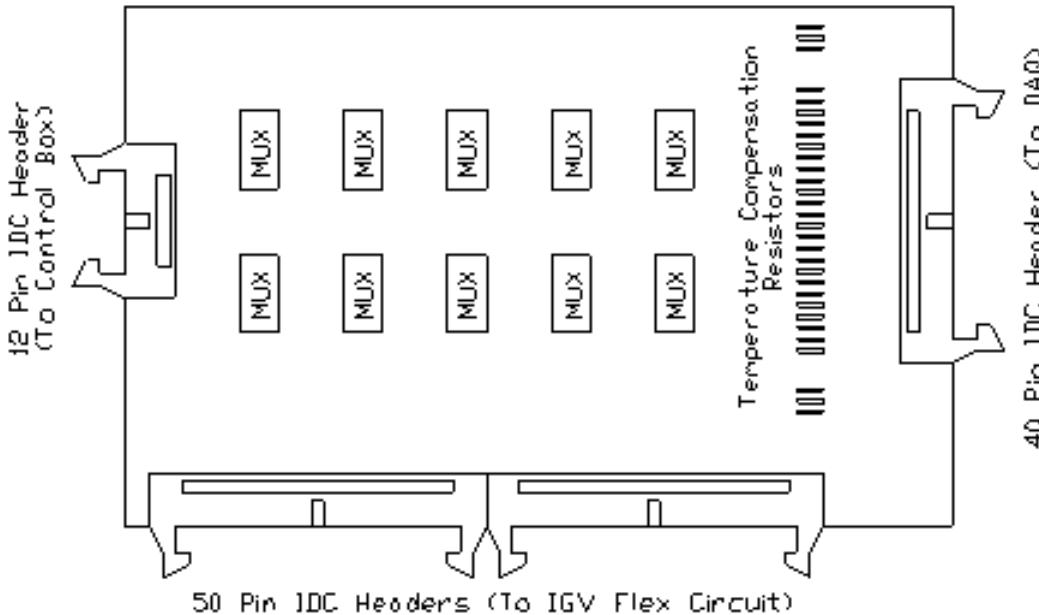
Pressure Transducer Dies



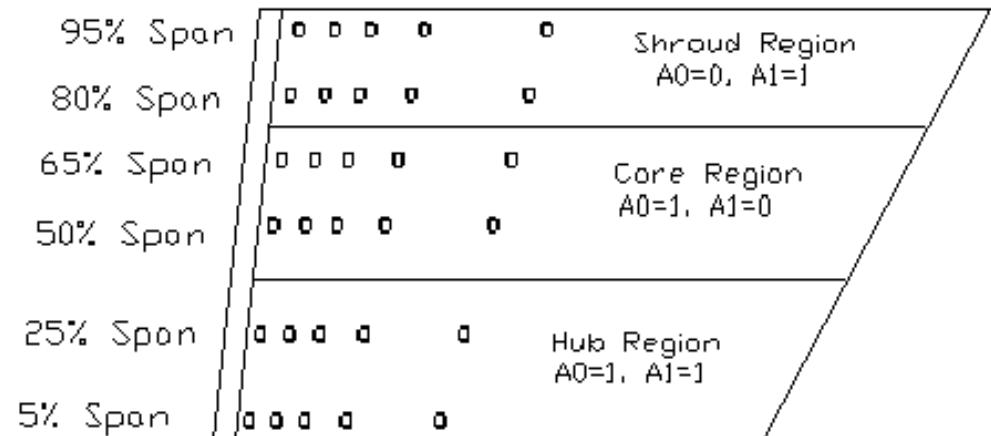


- 30 mil slot machined in IGV
- Rubber sheet fills between sensor dies
- Silicon gel & kapton tape used to contour surface

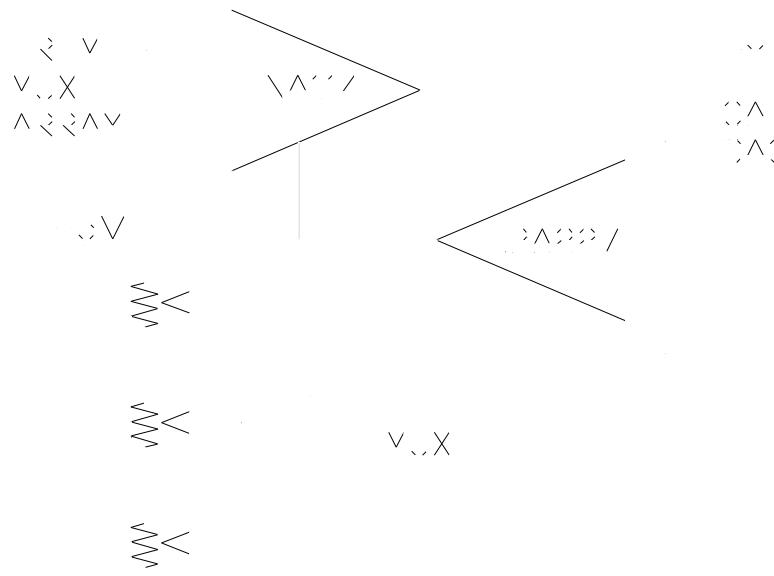
Multiplexed Array



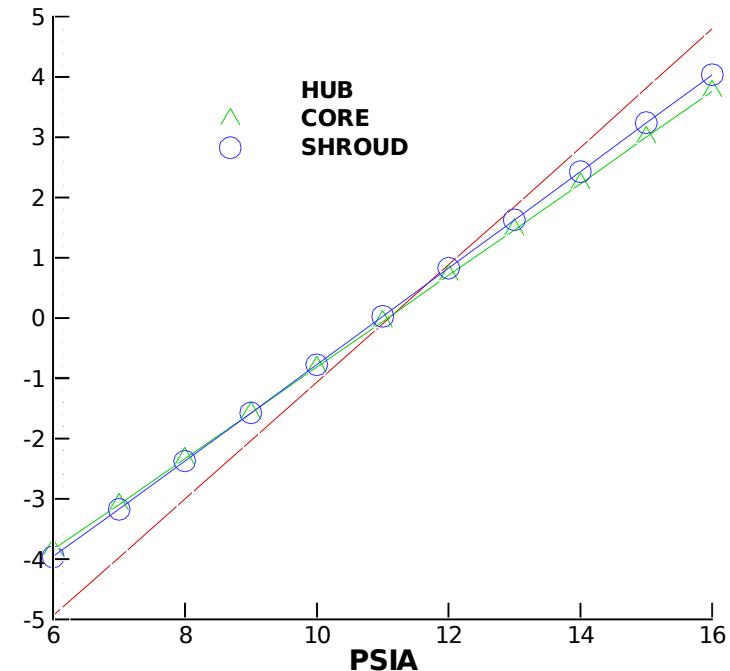
- 2-Board design (stackable)
- 10 MUX/board
- Incorporates thermal compensation resistors
- Remotely controllable



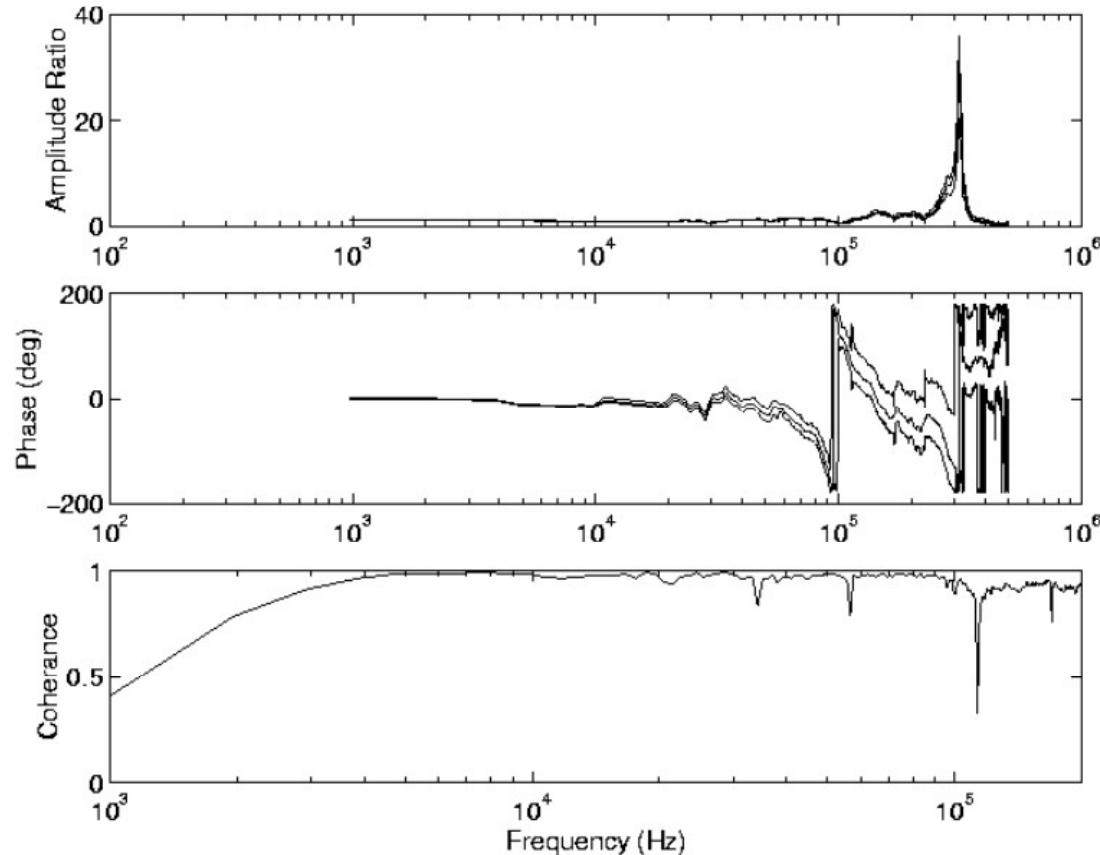
Trimmer Circuit &



DAQ Channel 1



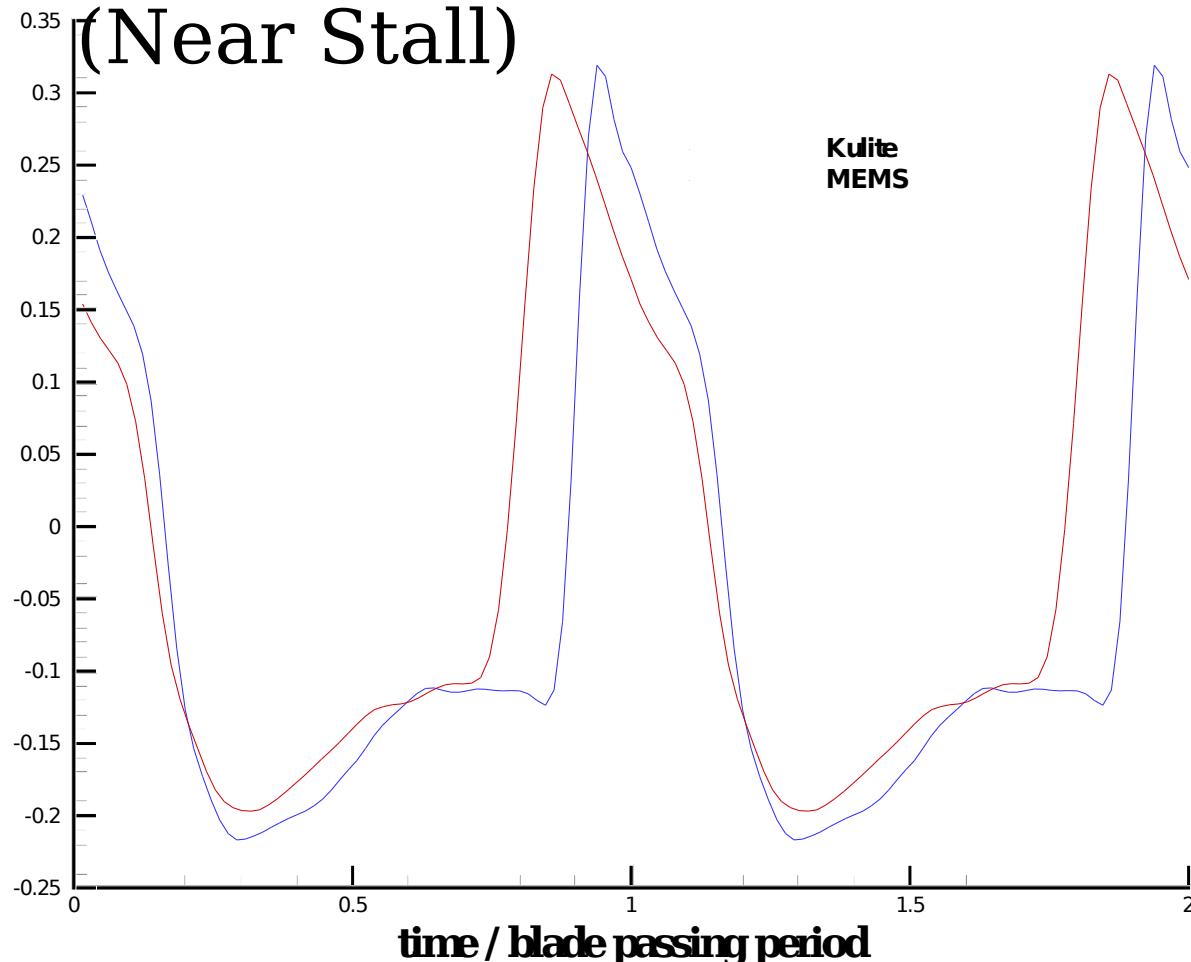
- Incorporation of the trimmer circuits allowed for a full DC signal to be obtained with the existing CARL DAQ system
- Static calibration showed excellent linearity of the MEMS pressure sensor array system



- WSU Shock Tube Testing
- Usable Frequency BW 30 kHz

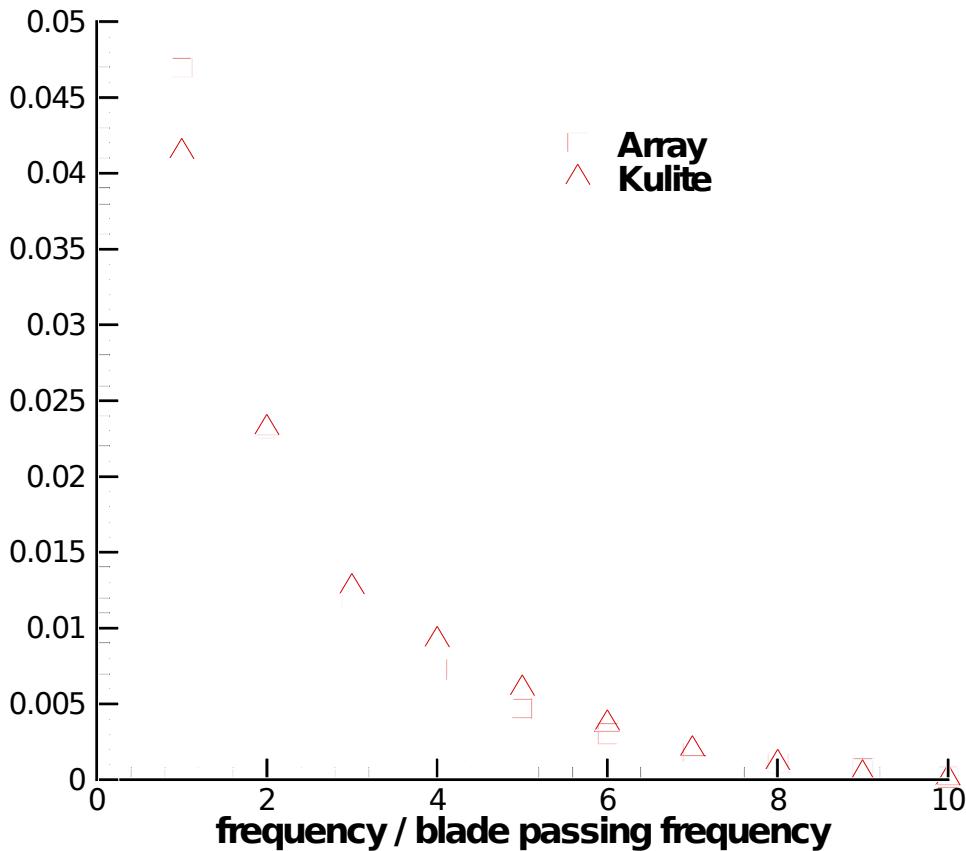
50% Span, 95% Chord, 105% Speed

(Near Stall)



- Favorable agreement with previous sensor data
- Slight phase shift caused by annular shift in physical sensor location

Preliminary Measurements



- 50% Span, 90% Chord, 105% Speed
- 8% variation in 1st harmonic amplitude
- Differences caused by uncertainty in matching test conditions with different ambient conditions

Summary & Conclusions

- MEMS Sensors Designed and Installed
 - 2 IGV blades instrumented - 60 total sensors
 - High spatial and temporal resolution
 - AC and DC pressure components obtained
- High-speed transonic compressor unsteady aerodynamics data
 - Excellent agreement with previous traditional sensors
 - Tip region flow physics including shock/boundary layer interaction measured
 - Spacing and throttle position influences were measured